11. 11			A.
	Application No.	Applicant(s)	
Notice of Allowability	09/015,287	NOZAKI ET AL.	
	Examiner	Art Unit	
	John S. Chu	1752	
The MAILING DATE of this communication ap All claims being allowable, PROSECUTION ON THE MERITS I herewith (or previously mailed), a Notice of Allowance (PTOL-8 NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT of the Office or upon petition by the applicant. See 37 CFR 1.3	S (OR REMAINS) CLOSED in 5) or other appropriate common RIGHTS. This application is s	n this application. If not include unication will be mailed in due c	d course. THIS
1. \square This communication is responsive to $2/10/04$.			
2. ☑ The allowed claim(s) is/are <u>1-23</u> .			
3. The drawings filed on are accepted by the Exami	ner.		
 4. Acknowledgment is made of a claim for foreign priority a) All b) Some* c) None of the: 1. Certified copies of the priority documents hat 2. Certified copies of the priority documents hat 3. Copies of the certified copies of the priority 	ive been received. ive been received in Application	on No	on from the
International Bureau (PCT Rule 17.2(a)).			
* Certified copies not received:			
Applicant has THREE MONTHS FROM THE "MAILING DATE noted below. Failure to timely comply will result in ABANDON THIS THREE-MONTH PERIOD IS NOT EXTENDABLE.		e a reply complying with the requ	uirements
5. A SUBSTITUTE OATH OR DECLARATION must be sub INFORMAL PATENT APPLICATION (PTO-152) which g			TICE OF
6. CORRECTED DRAWINGS (as "replacement sheets") m	nust be submitted.		
(a) including changes required by the Notice of Draftspo		w (PTO-948) attached	
1) hereto or 2) to Paper No./Mail Date			
(b) including changes required by the attached Examine Paper No./Mail Date	er's Amendment / Comment o	r in the Office action of	
Identifying indicia such as the application number (see 37 CFF each sheet. Replacement sheet(s) should be labeled as such i			back) of
 DEPOSIT OF and/or INFORMATION about the depattached Examiner's comment regarding REQUIREMEN 			ote the
Attachment(s)			
1. ⊠ Notice of References Cited (PTO-892)	5. Notice of Ir	nformal Patent Application (PTO	-152)
2. ☐ Notice of Draftperson's Patent Drawing Review (PTO-948		Summary (PTO-413),	
 Information Disclosure Statements (PTO-1449 or PTO/St Paper No./Mail Date 	3/08), 7. ☐ Examiner's	/Mail Date Amendment/Comment	
4. Examiner's Comment Regarding Requirement for Deposi		Statement of Reasons for Allov	vance
of Biological Material	9. 🗌 Other	_·	
		John S. Chu Primary Examiner Art Unit: 1752	

U.S. Patent and Trademark Office PTOL-37 (Rev. 1-04) Application/Control Number: 09/015,287

Page 2

Art Unit: 1752

REASONS FOR ALLOWANCE

1. The following is an examiner's statement of reasons for allowance: The claimed invention is drawn to the following:

- An acid-sensitive polymer compound, comprising:
 - a film-forming polymer;
- a carboxyl group bonding to a side chain of said polymer main chain, said carboxyl group having a protective group; and

an additional acidic functional group bonding to a side chain of said polymer main chain, said acidic functional group having an acid-cleavable protective group;

said carboxyl group having, as said
protective group, a lactone structure represented by a
formula

$$\int_{0}^{R}$$

wherein n is an integer of 1 - 4, and R represents any of a hydrogen atom, an alkyl group, an alkoxyl group or an alkoxycarbonyl group and bonding to an arbitrary position of said lactone structure excluding a second position forming an ester bonding.

8. A resist composition, comprising:

an acid-sensitive film-foming polymer insoluble to an alkaline solution; a carboxyl group bonding to a side chain of said polymer's main chain, said carboxyl group having a protective group; and an additional acidic functional group bonding to a side chain of said polymer main chain, said acidic functional group having an acid-cleavable protective group; said carboxyl group having, as said protective group, a lactone structure represented by a formula

Application/Control Number: 09/015,287 Page 3

Art Unit: 1752

wherein n is an integer of 1 - 4, and R represents any of a hydrogen atom, an alkyl group, an alkoxyl group or an alkoxycarbonyl group and bonding to an arbitrary position of said lactone structure excluding a second position forming an ester bonding; and

a photoacid generator causing a decomposition in response to an absorption of a radiation, said photoacid generator releasing an acid that causes a deprotection of said acid-cleavable protective group in response to said decomposition;

said resist composition becoming soluble to said alkaline solution after said acid-cleavable protective group has caused said deprotection.

Applicants have argued that the claims are not anticipated by the prior art of NOZAKI et al '416 as explained in the response received February 10, 2004, wherein the prior art mevalonic lactone group is different from the claimed 2-hydroxy-alkylolactone group used to make the copolymer having the formula in claim 1. The examiner concurs with the applicant and withdraws the rejection over NOZAKI et al '416.

Newly cited reference to TAKECHI et al is to the same assignee of *Fujitsu Limited* having a filing date of April 24, 1998. This reference is not available as prior art under 102 or 103 due to a later filing date. However, the reference was considered for an obviousness-type double patenting rejection, however the claimed chemically amplified resist material to the polymer recited a terpolymer has three monomer groups, while the claims to the current application are to a copolymer and a resist material comprising a copolymer having two monomeric groups. There is no motivation present in the prior art to remove the first monomer claimed in TAKECHI et al, which is protected with an alicyclic hydrocarbon monomer to arrive

Art Unit: 1752

at the claimed copolymer of the current application. Further there is no motivation in the prior art for one of ordinary skill to add a monomer having an alicyclic hydrocarbon to the copolymer of the current application to arrive at a terpolymer as claimed TAKECHI et al.

Because none of the prior art references of record disclose the claimed acid polymer, the resist composition or the method of forming a pattern, claims 1-23 are seen as allowable and passed to issue.

Any comments considered necessary by applicant must be submitted no later than the 2. payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Examiner Chu whose telephone number is (571) 272-1329. The examiner can normally be reached on Monday - Friday from 9:30 am to 6:00 pm.

The fax phone number for the USPTO is (703) 872-9306.

Any inquiry of a general nature or relating to the status of this application or proceeding should be directed to the Group receptionist whose telephone number is (571) 272-1700.

mary Examiner, Group 1700

J.Chu April 17, 2004